

**IN THE
UNITED STATES
PATENT AND TRADEMARK OFFICE**

**IN RE APPLICATION
OF:**

Thorsten Lower

CASE:

OST-031107

SER. NO.:

10/619,933

FILING DATE:

July 15, 2003

FOR:

METHOD FOR MEASURING THE INTENSITY
PROFILE OF AN ELECTRON BEAM, IN
PARTICULAR A BEAM OF AN ELECTRON-
BEAM MACHINING DEVICE...

RESPONSE TO
OFFICE
ACTION

Mail Stop: Amendment
COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, VA 22313-1450

Examiner:
J. J. LEYBOURNE
Art Unit
2881

Dear Examiner:

If any charges or fees must be paid in connection with the following communication, they may be paid out of our Deposit Account No. 50-0545.

In response to the Office Action of November 01, 2004, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks/Arguments begin on page 12 of this paper.

~~05/05/2005-AKELECH1-00000021-10619933~~ 05/05/2005 AKELECH1 00000021 10619933

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625.00 OP

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